

AMC200 | 200 mm Manual Analytical Probe Station For True DC/CV and RF measurements

FEATURES / BENEFITS

- \blacksquare Manual stage assembly with up to 200mm x 200mm range of motion
- ♣ Powder-coated steel platen holds up to 8 magnetic or vacuum-based positioners.
- ♣ High quality stereo zoom/compound microscopes with high-intensity LED lighting provide outstanding vision at magnifications. Includes camera port
- ♣ Standard boom/bridge

 mounts assembly for full
 range XYZ positioning of



- microscope. XY range of 25mm x25mm (higher range available).
- **4** Available high resolution micropositioners
- **♣** Compatible for the temperature Range:-70°C to 300°C
- **♣** RF options available (Up to 67 GHz) include customizable RF probes, RF bias-able chuck, and shielding enclosures

SPECIFICATIONS

Chuck XYZ Stage Travel:





Chuck Theta travel : $\pm 5^{\circ}$

Chuck Pull Out Stage : pull out Stage

LATEN:

Specifications:

Material : Stainless Steel

Chuck to platen height : Min. 10 mm

Platen lift control : Fixed, Platen lift of up 20 mm available on

request(Optional)

Max. No of Micro-Positioners : Up to 4DC and 4 RF Positioners

Micropositioners Mounting : Compatible for both Magnetic as well as Vacuum

base micropositioners

RF Micro-Positioner mounting : Magnetic/Vacuum base with guided rail

DC Micro-Positioner mounting : Magnetic/Vacuum base

♣ NON-THERMAL CHUCKS

Standard Wafer Chuck:

Chuck Connections : Coaxial(BNC)/ Triaxial

Chuck Diameter : Up to 200 mm

Chuck Material : Stainless Steel. Chuck made of other material is

available as optional

Chuck surface : Planar with centric engraved vacuum grooves

Chuck Sample actuation : Vacuum actuation with three zone vacuum holes

Sample Size : Min 5mm x 5mm up to 200 mm wafer

Chuck Surface Planarity : $10\mu m$, Optional down to $\pm 3\mu m$

RF Wafer Chuck:

Chuck Connections : Coaxial(BNC)

Chuck Diameter : Up to 200 mm 2 AUX chuck as optional

Chuck Material : Nickel Plated aluminum, Ceramic etc

Chuck surface : Planar with centric engraved vacuum grooves

Chuck Sample actuation : Vacuum actuation with three zone vacuum holes

Sample Size : Min 5mm x 5mm up to 200 mm wafer

Chuck Surface Planarity : $10\mu m$, Optional down to $\pm 3\mu m$

DATASHEET



Auxiliary Chuck:

Quantity : 2 Nos of AUX Chuck

Chuck Diameter : Up to 100 mm

Chuck Material : Derlin, Ceramic, RF absorbing material

Chuck Sample actuation : Separate vacuum control switches for auxiliary

chucks

Sample Size : Min 5mm x 5mm up to 100 mm wafer

Chuck Surface Planarity : $10\mu m$, Optional down to $\pm 3\mu m$

Micro-Chamber:

EMI shielding : >20 dB 0.5-20 GHz

Spectral noise floor : < -150 dBVrms/rtHz

System AC noise : < 15 mVp-p

Light Shielding:

Type : Dark enclosure around chuck

Wafer access : Pullout stage for easy wafer loading access with

Front opening door

Probe compatibility : Micro-Chamber compatible for up to eight

Micropositioners (Probes)

Light attenuation : > 120 dB

Purge and Condensation Control:

Dew point capability : Frost free measurements: Up to -70°C

Purging gas : Dry air or nitrogen

Purging flow rate : Standard purge - manual controls, variable 0 to 110

1/min

Quick Purge Control: 0 or maximum air flow

Purging time : < 15 min @ -55°C

LECTRICAL SPECIFICATIONS:

Standard Chuck @10 V:

Parameter	Coaxial Chuck	Triaxial Ch	uck
Maximum voltage between chuck and GND	500 V DC	500 V D	С
Isolation	$> 2 G\Omega$		
		Force to guard	$> 25T\Omega$
		Guard to shield	> 3T



DATASHEET



		Force to shield	> 500GΩ
Leakage current	< 50pA	≤ 50fA	
Capacitance	< 800pF	< 100fF	
Chuck Flatness	≤10μm	≤10µm	

4 Thermal Chuck:

Parameter	Coaxial Chuck	Triaxial Chuck
Temperature Control	Resistive type heating	Resistive type heating
Method		
Cooling	Air cooling/Water cooling	Air cooling/Water cooling
Temperature Range	RT - 200°C, Optional up to 600°C	RT - 200°C, Optional up to 600°C
Temperature Control	Linear DC/PID	Linear DC/PID
Temperature Sensor	(RTD) Pt100//3DIN, 4-line wired	(RTD) Pt100//3DIN, 4-line wired
Temperature Stability	±0.5 °C	±0.5 °C
Temperature Accuracy	±1 °C	±1 °C
Connection Interface	RS232	RS232
Chuck Surface Plating	Nickel/Gold	Nickel/Gold
Surface Flatness	$\pm 10 \mu m@RT \& \le 30 \mu m@ \ge 300^{\circ}$	$\pm 10 \mu m@RT \& \le 30 \mu m@ \ge 300^{\circ}C$
Leakage Current	< 100pA	<100fA

HOT and COLD CHUCK:

Parameter	Coaxial Chuck	Triaxial Chuck
Temperature Control	Peltier (-30°C to 140°C)/	Peltier (-30°C to 140°C)/
Method	Air Cool(-70°C to 200°C)/	Air Cool (-70°C to 200°C)/
	Liquid cool(-70°C to 200°C)	Liquid cool (-70°C to 200°C)
Temperature Range	-70°C - 200°C	-70°C - 200°C
Temperature Accuracy	±0.5 °C	±0.5 °C
Temperature Stability	±1 °C	±1 °C
Connection Interface	RS232/RS484	RS232/RS485
Chuck Surface Plating	Copper plated with Nickel/Gold	Copper Plated with Nickel/Gold
Leakage Current	< 100pA	<100fA
Nitrogen or CDA purge to avoid frost free characterization		



Micropositioners:

Model	Description	
MH100	Fixed Magnet Base Switchable Magnet Base Vacuum Base	
MH100	Foot dimension Travel range X,Y Travel range Z Feature Resolution TPI resolution	70 x 50mm 12mm 8mm 1μm/0.8μm 80 TPI/100TPI
МН300	Fixed Magnet Base Switchable Magnet Base Vacuum Base	
MH300	Foot dimension Travel range X,Y Travel range Z Feature Resolution	70 x 35mm 12mm 12mm 3μm
MH500	Switchable magnet base Vacuum Base	
MH500	Foot dimension Travel range X, Y Travel range Z Feature Resolution	80 x 90mm ±15 mm ±15 mm 3μm

4 Probe Tip Holders with Connecting Cable:

Model	Description
Coaxial Tip Holder with Coaxial Cable	
SHC15	Spring Holder/1.5m coax cable/BNC male
THC15	Tube Holder/1.5m coax cable/BNC male
NHC15	Nut Holder/1.5m coax cable/BNC male
Triaxial Tip Holder with Triaxial Cable	
THT15	Tube Holder/1.5m Triax cable/Triax male
NHT15	Nut Holder/1.5m Triax cable/Triax male
High Frequency Probe Arms	
MWA-EW	HF probe arm (east-west)
MWA-NS	HF probe arm(north - south)

System Dimensions: 580mm wide x460mm deep x 245mm high

Weight: 100kg to 200kg depending on options selected